

Contents

Preface to the First Edition	<i>XVII</i>
Preface to the Second Edition	<i>XIX</i>
List of Contributors	<i>XXI</i>

1	Introduction	<i>1</i>
	<i>John C. Rivière and Henning Bubert</i>	

Part One Electron Detection 7

2	X-Ray Photoelectron Spectroscopy (XPS)	<i>9</i>
	<i>Henning Bubert, John C. Rivière, and Wolfgang S.M. Werner</i>	
2.1	Principles	<i>9</i>
2.2	Instrumentation	<i>12</i>
2.2.1	Vacuum Requirements	<i>12</i>
2.2.2	X-Ray Sources	<i>13</i>
2.2.3	Synchrotron Radiation	<i>16</i>
2.2.4	Electron Energy Analyzers	<i>16</i>
2.2.5	Spatial Resolution	<i>18</i>
2.3	Spectral Information and Chemical Shifts	<i>19</i>
2.4	Quantification, Depth Profiling, and Imaging	<i>21</i>
2.4.1	Quantification	<i>21</i>
2.4.2	Depth Profiling	<i>23</i>
2.4.3	Imaging	<i>26</i>
2.5	The Auger Parameter	<i>27</i>
2.6	Applications	<i>28</i>
2.6.1	Catalysis	<i>28</i>
2.6.2	Polymers	<i>30</i>
2.6.3	Corrosion and Passivation	<i>31</i>
2.6.4	Adhesion	<i>32</i>
2.6.5	Superconductors	<i>34</i>
2.6.6	Semiconductors	<i>35</i>

2.7	Ultraviolet Photoelectron Spectroscopy (UPS)	38
	References	39
3	Auger Electron Spectroscopy (AES)	43
	<i>Henning Bubert, John C. Rivière, and Wolfgang S.M. Werner</i>	
3.1	Principles	43
3.2	Instrumentation	44
3.2.1	Vacuum Requirements	44
3.2.2	Electron Sources	44
3.2.3	Electron-Energy Analyzers	45
3.3	Spectral Information	47
3.4	Quantification and Depth Profiling	51
3.4.1	Quantification	51
3.4.2	Depth Profiling	53
3.5	Applications	54
3.5.1	Grain Boundary Segregation	54
3.5.2	Semiconductor Technology	56
3.5.3	Thin Films and Interfaces	58
3.5.4	Surface Segregation	58
3.6	Scanning Auger Microscopy (SAM)	61
	References	64
4	Electron Energy-Loss Spectroscopy (EELS) and Energy-Filtering Transmission Electron Microscopy (EFTEM)	67
	<i>Reinhard Schneider</i>	
4.1	Principles	68
4.2	Instrumentation	70
4.3	Qualitative Spectral Information	72
4.3.1	Low-Loss Excitations	74
4.3.2	Ionization Losses	77
4.3.3	Fine Structures	79
4.4	Quantification	83
4.5	Imaging of Element Distribution	85
4.6	Summary	88
	References	89
5	Low-Energy Electron Diffraction (LEED)	93
	<i>Georg Held</i>	
5.1	Principles and History	93
5.2	Instrumentation	94
5.3	Qualitative Information	96
5.3.1	LEED Pattern	96
5.3.2	Spot Profile Analysis	100
5.3.3	Applications and Restrictions	100
5.4	Quantitative Structural Information	101

5.4.1	Principles	101
5.4.2	Experimental Techniques	102
5.4.3	Computer Programs	104
5.4.4	Applications and Restrictions	105
5.5	Low-Energy Electron Microscopy	106
5.5.1	Principles of Operation	106
5.5.2	Applications and Restrictions	108
	References	108
6	Other Electron-Detecting Techniques	111
	<i>John C. Rivière</i>	
6.1	Ion (Excited) Auger Electron Spectroscopy (IAES)	111
6.2	Ion Neutralization Spectroscopy (INS)	111
6.3	Inelastic Electron Tunneling Spectroscopy (IETS)	112
	Reference	113

Part Two Ion Detection 115

7	Static Secondary Ion Mass Spectrometry (SSIMS)	117
	<i>Heinrich F. Arlinghaus</i>	
7.1	Principles	117
7.2	Instrumentation	119
7.2.1	Ion Sources	119
7.2.2	Mass Analyzers	120
7.2.2.1	Quadrupole Mass Spectrometers	120
7.2.2.2	Time-of-Flight Mass Spectrometry (TOF-MS)	121
7.3	Quantification	123
7.4	Spectral Information	125
7.5	Applications	127
7.5.1	Oxide Films	128
7.5.2	Interfaces	128
7.5.3	Polymers	131
7.5.4	Biosensors	133
7.5.5	Surface Reactions	134
7.5.6	Imaging	135
7.5.7	Ultra-Shallow Depth Profiling	137
	References	138
8	Dynamic Secondary Ion Mass Spectrometry (SIMS)	141
	<i>Herbert Hutter</i>	
8.1	Principles	141
8.1.1	Compensation of Preferential Sputtering	141
8.1.2	Atomic Mixing	142
8.1.3	Implantation of Primary Ions	142

8.1.4	Crater Bottom Roughening	142
8.1.5	Sputter-Induced Roughness	142
8.1.6	Charging Effects	142
8.2	Instrumentation	143
8.2.1	Ion Sources	143
8.2.1.1	Duoplasmatron	144
8.2.2	Mass Analyzer	144
8.2.2.1	Magnetic Sector Field	144
8.2.2.2	Detector	145
8.3	Spectral Information	146
8.4	Quantification	147
8.4.1	Relative Sensitivity Factors	147
8.4.2	Implantation Standards	147
8.4.3	Metal Cesium (MCs ⁺) Ions	148
8.4.4	Theoretical Models	148
8.4.4.1	Electron Tunneling Model	148
8.4.4.2	Broken Bond Model	148
8.4.4.3	Local Thermodynamic Equilibrium LTE	148
8.5	Mass Spectra	149
8.6	Depth Profiles	149
8.6.1	Dual-Beam Technique for TOF-SIMS Instruments	152
8.6.2	Molecular Depth Profiles	152
8.7	Imaging	152
8.7.1	Scanning SIMS	152
8.7.2	Direct Imaging Mode	153
8.8	Three-Dimensional (3-D)-SIMS	154
8.9	Applications	156
8.9.1	Implantation Profiles	156
8.9.2	Layer Analysis	157
8.9.3	3-D Trace Element Distribution	158
	References	159

9 **Electron-Impact (EI) Secondary Neutral Mass Spectrometry (SNMS)** 161

Michael Kopnarski and Holger Jenett

9.1	Introduction	161
9.2	General Principles of SNMS	162
9.2.1	Postionization via Electron Impact	163
9.2.2	Suppression of Residual Gas and Secondary Ions	164
9.3	Instrumentation and Methods	166
9.3.1	Electron Beam SNMS	166
9.3.2	Plasma SNMS	167
9.4	Spectral Information and Quantification	170
9.5	Element Depth Profiling	172

9.6	Applications	174
	References	175
10	Laser Secondary Neutral Mass Spectrometry (Laser-SNMS)	179
	<i>Heinrich F. Arlinghaus</i>	
10.1	Principles	179
10.1.1	Nonresonant Laser-SNMS	179
10.1.2	Resonant Laser-SNMS	179
10.1.3	Experimental Set-Up	180
10.1.4	Ionization Schemes	181
10.2	Instrumentation	182
10.3	Spectral Information	183
10.4	Quantification	183
10.5	Applications	184
10.5.1	Nonresonant Laser-SNMS	184
10.5.2	Resonant Laser-SNMS	186
	References	189
11	Rutherford Backscattering Spectroscopy (RBS)	191
	<i>Leopold Palmetshofer</i>	
11.1	Introduction	191
11.2	Principles	191
11.3	Instrumentation	194
11.4	Spectral Information	194
11.5	Quantification	196
11.6	Figures of Merit	197
11.6.1	Mass Resolution	197
11.6.2	Sensitivity	198
11.6.3	Depth Resolution	198
11.6.4	Accuracy	198
11.7	Applications	198
11.8	Related Techniques	201
	References	201
12	Low-Energy Ion Scattering (LEIS)	203
	<i>Peter Bauer</i>	
12.1	Principles	203
12.2	Instrumentation	206
12.3	LEIS Information	208
12.3.1	Energy Information	208
12.3.2	Yield Information	208
12.4	Quantification	211
12.5	Applications of LEIS	211
	References	214

13	Elastic Recoil Detection Analysis (ERDA)	217
	<i>Oswald Benka</i>	
13.1	Introduction	217
13.2	Fundamentals	218
13.3	Particle Identification Methods	220
13.4	Equipment	222
13.5	Data Analysis	223
13.6	Sensitivity and Depth Resolution	223
13.7	Applications	224
	References	226
14	Nuclear Reaction Analysis (NRA)	229
	<i>Oswald Benka</i>	
14.1	Introduction	229
14.2	Principles	231
14.3	Equipment and Depth Resolution	232
14.4	Applications	234
	References	236
15	Field Ion Microscopy (FIM) and Atom Probe (AP)	237
	<i>Yuri Suchorski and Wolfgang Drachsel</i>	
15.1	Introduction	237
15.2	Principles and Instrumentation	239
15.2.1	Field Ion Microscopy	239
15.2.2	Time-of-Flight Atom Probe Techniques	242
15.2.3	Field Ion Appearance Energy Spectroscopy	246
15.3	Applications	248
15.3.1	FIM Applications	248
15.3.1.1	FIM in Catalysis	248
15.3.1.2	Fluctuation-Induced Effects	249
15.3.2	Applications of AP Techniques	252
15.3.2.1	Applications of TOF-AP Techniques	252
15.3.2.2	PFDMS Applications	254
15.3.2.3	FIAES Applications	255
	References	257
16	Other Ion-Detecting Techniques	261
	<i>John C. Rivière</i>	
16.1	Desorption Methods	261
16.1.1	Electron-Stimulated Desorption (ESD) and ESD Ion Angular Distribution (ESDIAD)	261
16.1.2	Thermal Desorption Spectroscopy (TDS)	262
16.2	Glow-Discharge Mass Spectroscopy (GD-MS)	263
16.3	Fast-Atom Bombardment Mass Spectroscopy (FABMS)	263
	References	264

Part Three Photon Detection 265

- 17 Total-Reflection X-Ray Fluorescence (TXRF) Analysis 267**
Laszlo Fabry, Siegfried Pahlke, and Burkhard Beckhoff
- 17.1 Principles 267
 - 17.2 Instrumentation 269
 - 17.3 Spectral Information 275
 - 17.4 Quantification 276
 - 17.5 Applications 277
 - 17.5.1 Particulate and Film-Type Surface Contamination 277
 - 17.5.2 Semiconductors 278
 - 17.5.2.1 Synchrotron Radiation-Based Techniques 280
 - 17.5.2.2 Depth Profiling by TXRF and by Grazing Incidence XRF (GIXRF) for the Characterization of Nanolayers and Ultra-Shallow Junctions 283
 - 17.5.2.3 Vapor-Phase Decomposition (VPD) and Droplet Collection 285
 - 17.5.2.4 Vapor-Phase Treatment (VPT) and Total Reflection X-Ray Fluorescence Analysis 287
 - References 288
- 18 Energy-Dispersive X-Ray Spectroscopy (EDXS) 293**
Reinhard Schneider
- 18.1 Principles 293
 - 18.2 Practical Aspects of X-Ray Microanalysis and Instrumentation 295
 - 18.3 Qualitative Spectral Information 303
 - 18.4 Quantification 304
 - 18.5 Imaging of Element Distribution 306
 - 18.6 Summary 308
 - References 309
- 19 Grazing Incidence X-Ray Methods for Near-Surface Structural Studies 311**
P. Neil Gibson
- 19.1 Principles 311
 - 19.1.1 The Grazing Incidence X-Ray Geometry 312
 - 19.1.2 Grazing Incidence X-Ray Reflectivity (GXRR) 314
 - 19.1.3 Glancing Angle X-Ray Diffraction 314
 - 19.1.4 ReflEXAFS 316
 - 19.2 Experimental Techniques and Data Analysis 317
 - 19.2.1 Grazing Incidence X-Ray Reflectivity (GXRR) 318
 - 19.2.2 Grazing Incidence Asymmetric Bragg (GIAB) Diffraction 319
 - 19.3 Applications 321
 - 19.3.1 Grazing Incidence X-Ray Reflectivity (GXRR) 321
 - 19.3.2 Grazing Incidence Asymmetric Bragg (GIAB) Diffraction 323
 - 19.3.3 Grazing Incidence X-Ray Scattering (GIXS) 324

19.3.4	ReflEXAFS	325
	References	326
20	Glow Discharge Optical Emission Spectroscopy (GD-OES)	329
	<i>Volker Hoffmann and Alfred Quentmeier</i>	
20.1	Principles	329
20.2	Instrumentation	330
20.2.1	Glow Discharge Sources	330
20.2.2	Spectrometer	334
20.2.3	Signal Acquisition	334
20.3	Spectral Information	335
20.4	Quantification	336
20.5	Depth Profiling	337
20.6	Applications	339
20.6.1	dc GD Sources	340
20.6.2	rf GD Sources	340
	References	342
21	Surface Analysis by Laser Ablation	345
	<i>Roland Hergenröder and Michail Bolshov</i>	
21.1	Introduction	345
21.2	Instrumentation	346
21.2.1	Types of Laser	346
21.2.2	Different Schemes of Laser Ablation	347
21.3	Depth Profiling	348
21.4	Near-Field Ablation	354
21.5	Conclusion	354
	References	355
22	Ion Beam Spectrochemical Analysis (IBSCA)	357
	<i>Volker Rupertus</i>	
22.1	Principles	357
22.2	Instrumentation	358
22.3	Spectral and Analytical Information	360
22.4	Quantitative Analysis by IBSCA	361
22.5	Applications	363
	References	366
23	Reflection Absorption IR Spectroscopy (RAIRS)	367
	<i>Karsten Hinrichs</i>	
23.1	Instrumentation	367
23.2	Principles	368
23.3	Applications	369
23.3.1	RAIRS	369
23.3.2	ATR and SEIRA	372

23.4	Related Techniques	374
	References	374
24	Surface Raman Spectroscopy	377
	<i>Wieland Hill and Bernhard Lendl</i>	
24.1	Principles	377
24.2	Surface-Enhanced Raman Scattering (SERS)	378
24.3	Instrumentation	380
24.4	Spectral Information	382
24.5	Quantification	383
24.6	Applications	383
24.6.1	Unenhanced Raman Spectroscopy at Smooth Surfaces	383
24.6.2	Porous Materials	385
24.6.3	Surface-Enhanced Raman Spectroscopy (SERS)	386
24.6.4	Near-Field Raman Spectroscopy	387
24.7	Nonlinear Optical Spectroscopy	387
24.7.1	Sum Frequency Generation (SFG) Spectroscopy	387
24.7.2	Coherent Anti-Stokes Raman Scattering (CARS)	389
24.7.3	Stimulated Femtosecond Raman Scattering (SFRS)	389
24.7.4	Spatially Offset Raman Spectroscopy (SORS)	390
	References	390
25	UV-VIS-IR Ellipsometry (ELL)	393
	<i>Bernd Gruska and Karsten Hinrichs</i>	
25.1	Principles	393
25.2	Instrumentation	395
25.3	Applications	398
25.3.1	UV-Vis-NIR Spectral Region	398
25.3.2	Infrared Ellipsometry	400
	References	405
26	Sum Frequency Generation (SFG) Spectroscopy	407
	<i>Günther Rupprechter and Athula Bandara</i>	
26.1	Introduction to SFG Spectroscopy	407
26.2	SFG Theory	410
26.2.1	SFG Signal Intensity and Lineshape	412
26.2.2	Determining the Number Density of Molecules from SFG Signal Intensity	413
26.3	SFG Instrumentation and Operation Modes	414
26.4	Applications of SFG Spectroscopy and Selected Case Studies	417
26.4.1	SFG Spectroscopy on Solid Surfaces and Solid–Gas Interfaces	417
26.4.1.1	SFG Spectroscopy under UHV Conditions	417
26.4.1.2	Polarization-Dependent SFG Spectroscopy	419
26.4.1.3	SFG Spectroscopy under Near-Atmospheric Gas Pressure	420
26.4.1.4	SFG Spectroscopy on Supported Metal Nanoparticles	421

26.4.1.5	Time-Resolved (Pump-Probe) and Broadband SFG Spectroscopy	423
26.4.1.6	SFG Spectroscopy on Colloidal Nanoparticles and Powder Materials	427
26.4.2	SFG Spectroscopy on Solid–Liquid Interfaces	428
26.4.3	SFG Spectroscopy on Polymer and Biomaterial Interfaces	428
26.4.4	SFG Spectroscopy at Liquid–Gas and Liquid–Liquid Interfaces	429
26.5	Conclusion	430
	References	430

27 Other Photon-Detecting Techniques 437

John C. Rivière

27.1	Appearance Potential Methods	437
27.1.1	Soft X-Ray Appearance Potential Spectroscopy (SXAPS)	437
27.2	Inverse Photoemission Spectroscopy (IPES) and Bremsstrahlung Isochromat Spectroscopy (BIS)	437

Part Four Scanning Probe Microscopy 439

28 Introduction 441

Gernot Friedbacher

References	442
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29 Atomic Force Microscopy (AFM) 443

Gernot Friedbacher

29.1	Principles	443
29.2	Further Modes of AFM Operation	446
29.2.1	Friction Force Microscopy (FFM)	446
29.2.2	Young's Modulus Microscopy (YMM) or Force Modulation Microscopy (FMM)	447
29.2.3	Phase Imaging	447
29.2.4	Force–Distance Curve Measurements	447
29.2.5	Pulsed Force Mode AFM	448
29.2.6	Harmonic Imaging and Torsional Resonance Mode	449
29.3	Instrumentation	452
29.4	Applications	455
	References	462

30 Scanning Tunneling Microscopy (STM) 465

Gernot Friedbacher

30.1	Principles	465
30.2	Instrumentation	467
30.3	Lateral and Spectroscopic Information	468
30.4	Applications	470
	References	479

31	Scanning Near-Field Optical Microscopy (SNOM)	481
	<i>Marc Richter and Volker Deckert</i>	
31.1	Introduction	481
31.2	Instrumentation and Operation	482
31.2.1	Basic Set-Up	482
31.2.2	Variations of SNOM	483
31.2.3	Scanning and Feedback Techniques	484
31.2.4	Tip Fabrication	485
31.2.4.1	Taper Formation	486
31.2.4.2	Coating Deposition and Aperture Formation	486
31.2.4.3	Advanced Tip Fabrication	487
31.3	SNOM Applications	488
31.3.1	Fluorescence	488
31.3.2	Near-Field Raman Spectroscopy	490
31.3.3	SNOM-IR-Spectroscopy	492
31.4	Outlook	493
	References	493
	Appendices	499
	Appendix A Summary and Comparison of Techniques	501
	Appendix B Surface and Thin-Film Analytical Equipment Suppliers	507
	Index	519

